ABSTRACT

A method for preparing a package that can effectively suppress surface alteration even in a sputtering target whose surface is likely to be altered by moisture such as a sputtering target comprising an oxide of boron is provided. A method for preparing a package of sputtering target, including a step 1 of housing a sputtering target in a first packaging bag made of a film having a water vapor permeability of 1 g/(m^2·24 h) or less, and then vacuum sealing an opening of the first packaging bag; and a step 2 of housing the first packaging bag which has been vacuum sealed in the step 1, in a second packaging bag made of a film having a water vapor permeability of 1 g/(m^2·24 h) or less, and then enclosing one or more cushion gases selected from a group consisting of air and inert gas in the second packaging bag, and sealing an opening of the second packaging bag.